P.01

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DATE:

October 13, 2003

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14 (fourteen) w/cover

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## Message

### **DOCKET GS149**

Please see attached: Amendment

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## CONFIDENTIALITY NOTICE

Patent Application 10/010,162

# IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant:

Fwu-luan Hshich et al.

Serial No.:

10/010,162

Filed:

November 20, 2001

Title:

Method Of Forming Narrow Trenches In Semiconductor Substrates

Art Unit:

2812

Examiner:

Angel Roman

Docket No.: GS 149

CENTRAL FAX CENTER

Via Facsimile 703-872-9318

OCT 1 4 2003

Commissioner for Patents PO Box 1450 Alexandria, VA 22313-1450



#### AMENDMENT

Sir:

In response to the Office Action dated July 11, 2003 (Paper No. 7), the time for response ending on Tuesday, October 14, 2003 (Monday October 13 being a Federal Holiday), kindly amend the above-identified application as follows. In addition, any deficiencies may be charged to deposit account No. 50-1047.